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Information disclosure Statement by applicant					Filing Date	«1/4/02	RECE	
					First Named Inventor	Steven Teig		AFD
					Group Art Unit	2661	OCT 2 1 2	003
(use as many sheets as necessary)					Examiner Name	<not yet=""></not>	Qed mology Ce	
Sheet	3	of	4		Attorney Docket Number	SPLX.P0047	Mogunach oc	iter 5000

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			RELATED	J.S. PATENT DOCU	IMENTS
M-ID	23.	2003/0115566	01-13-2002 03-2-0-3	Steven Teig	Application with some of the same parent provisional and non-provisional applications.
7	24.	2003/0056187 S/N 10/047,982	01-14-2002	Steven Teig et al.	Application with some of the same parent provisional and non-provisional applications.
	25.	Preliminary Amendment S/N 10/047,982	01-14-002	Steven Teig et al.	This Preliminary Amendment is submitted as the publication 2003/0056187 does not accurately reflect the claims of S/N 10/047,982
	26.	2003/0086044	01-13-2002 05 - 203	Steven Teig et al.	Application with some of the same parent provisional and non-provisional applications.
	27.	2003/0066045	01-13-2002	Steven Telg et al.	Application with some of the same parent provisional and non-provisional applications.
	28.	2003/0088845 S/N 10/047,978	01-13-2002	Steven Teig et al.	Application with some of the same parent provisional and non-provisional applications.
	29.	Preliminary Amendment for S/N 10/047,978	01-13-2002	Steven Teig et al.	This Preliminary Amendment is submitted as the publication 2003/0088845 does not accurately reflect the claims of S/N 10/047,978.
	30.	2002/0133798	12-08-2000	Steven Teig et al.	Application regarding related placement technology.
	31.	2002/0100007	12-06-2200	Steven Telg et al.	Application regarding related placement technology.
	32.	2002/0073390 S/N 09/737,210	12-13-2000	Steven Teig et al.	Application regarding related placement technology.
	33.	Preliminary Amendment S/N 09/737,210	12-13-2000	Steven Teig et al.	This Preliminary Amendment is submitted as the publication 2002/0073390 does not accurately reflect the claims of S/N 09/737,210.
	34.	S/N 09/737,220	12-13-2000	Steven Telg et al.	Application regarding related placement technology.
1	35.	S/N 09/737,245	12-13-2000	Steven Teig et al.	Application regarding related placement technology.

MR, 10-11-00

Examiner Signature Date Considered

\* EXAMINER: Initial if reference existed of unetter or not citation is in conformance with MPEP 609. Draw line through citation if got in conformance and not considered, include copy of this form with Lebst communication to applicant. \*Applicant's unique citation designation number(optional). \*See Kinds Codes of USPTO Patent Documents at <a href="https://www.usoto.gov">www.usoto.gov</a> or MPEP 901.04. \*Enter Office that issued the document, by the two-letter code (WIPO Standard ST.3). \*For Japanese patent documents, the indication of the year of the relign of the Emperor must precede the serial number of the patent document. \*Kind of document by the appropriate symbols as indicated on the document under WIPO Standard ST. 18 if possible. \*Applicant is to place a check mark here if English language Transition is attached.

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